L Number	Hits	Search Text	DB	Time stamp
-	1	(seo near2 kwang-hun).in.	USPAT;	2004/05/12 15:41
			US-PGPUB;	
			EPO; JPO;	
			DERWENT:	
			IBM_TDB	
_	112708	(samsung and electronics).as.	USPAT;	2004/05/12 15:28
	112700	Courteding and clock childs.	US-PGPUB:	200 1/00/12 10:20
			EPO; JPO;	
			DERWENT;	
			IBM_TDB	
	4	((samsung and electronics).as.) and (wet adj clean adj station)	USPAT;	2004/05/12 15:33
-	4	((Samsung and electronics).as.) and (wet adjiclean adjistation)	US-PGPUB;	2004/05/12 15.55
			EPO; JPO;	
			DERWENT;	
	00	(/	IBM_TDB	0004/05/40 45 00
-	23	((samsung and electronics).as.) and (fixing adj guide)	USPAT;	2004/05/12 15:33
1			US-PGPUB;	
			EPO; JPO;	
		·	DERWENT;	
			IBM_TDB	
-	4	((samsung and electronics).as.) and ((fixing adj guide) with	USPAT;	2004/05/12 15:34
		sensor)	US-PGPUB;	
			EPO; JPO;	
			DERWENT;	
			IBM_TDB	
_	1	(wet adj clean adj (bath or station)) with (optical adj fiber) with	USPAT;	2004/05/12 15:50
-		sensor	US-PGPUB;	
1			EPO; JPO;	
			DERWENT;	
			IBM_TDB	
_	128	((bath or station)) with (optical adj fiber) with sensor	USPAT;	2004/05/12 15:50
	120	((butto or station)) with (option and liber) with school	US-PGPUB;	200-700/12 10.00
1			EPO; JPO;	
			DERWENT;	
İ				
	33	(//hath an atation)) with (antical adj fibor) with according	IBM_TDB	2004/05/40 45.50
-	33	(((bath or station)) with (optical adj fiber) with sensor) and	USPAT;	2004/05/12 15:58
		(semiconductor or wafer or substrate)	US-PGPUB;	
			EPO; JPO;	
			DERWENT;	
	_		IBM_TDB	
-	2	(((bath or station)) with (optical adj fiber) with sensor) and	USPAT;	2004/05/12 16:05
		((discharg\$3 or vent\$3 or remov\$3) with (dew or condensation	US-PGPUB;	
		or vapor or moisture))	EPO; JPO;	
1			DERWENT;	
			IBM_TDB	
-	3147	optical adj fiber adj sensor	USPAT;	2004/05/12 15:57
			US-PGPUB;	
			EPO; JPO;	
			DERWENT;	
			IBM_TDB	
-	203	(optical adj fiber adj sensor) and (sensor with above) and	USPAT;	2004/05/12 15:57
		(sensor with below)	US-PGPUB;	
			EPO; JPO;	
			DERWENT;	
			IBM TDB	
_	92	((optical adj fiber adj sensor) and (sensor with above) and	USPAT;	2004/05/12 15:58
		(sensor with below)) and (semiconductor or wafer or substrate)	US-PGPUB;	=30 1/00/12 10:00
ŀ		Commonwell of Waler of Substitute	EPO; JPO;	
ŀ			DERWENT;	
	64	(((antical adi fibor adi conser) and (conservitte at a conservit	IBM_TDB	2004/05/40 45 55
-	64	(((optical adj fiber adj sensor) and (sensor with above) and	USPAT;	2004/05/12 15:59
		(sensor with below)) and (semiconductor or wafer or	US-PGPUB;	
		substrate)) and ((sens\$3 or detect\$3) with (semiconductor or	EPO; JPO;	
		wafer or substrate))	DERWENT;	
	d		IBM_TDB	

-	4857	(sens\$3 or detect\$3) with ((discharg\$3 or vent\$3 or remov\$3 or purg\$3) with (dew or condensation or vapor or moisture))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2004/05/12 16:09
. –	2750	((sens\$3 or detect\$3) with ((discharg\$3 or vent\$3 or remov\$3 or purg\$3) with (dew or condensation or vapor or moisture))) and ((discharg\$3 or vent\$3 or remov\$3 or purg\$3) near2 (dew or condensation or vapor or moisture))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2004/05/12 16:07
-	31	(((sens\$3 or detect\$3) with ((discharg\$3 or vent\$3 or remov\$3 or purg\$3) with (dew or condensation or vapor or moisture))) and ((discharg\$3 or vent\$3 or remov\$3 or purg\$3) near2 (dew or condensation or vapor or moisture))) and 134/\$.ccls.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/12 16:07
-	23	(((sens\$3 or detect\$3) with ((discharg\$3 or vent\$3 or remov\$3 or purg\$3) with (dew or condensation or vapor or moisture))) and ((discharg\$3 or vent\$3 or remov\$3 or purg\$3) near2 (dew or condensation or vapor or moisture))) and ((sens\$3 or detect\$3) adj (housing or unit)) with ((discharg\$3 or vent\$3 or remov\$3 or purg\$3) with (dew or condensation or vapor or moisture))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/13 11:57
-	16	(optical adj fiber adj sensor) and ((discharg\$3 or vent\$3 or remov\$3 or purg\$3) with (dew or condensation or moisture))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/13 11:59
	1122	sensor with ((discharg\$3 or vent\$3 or remov\$3 or purg\$3) with (dew or condensation or moisture))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/13 11:59
_	62	sensor with housing with ((discharg\$3 or vent\$3 or remov\$3 or purg\$3) with (dew or condensation or moisture))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/13 12:00
-	6	(sensor with housing with ((discharg\$3 or vent\$3 or remov\$3 or purg\$3) with (dew or condensation or moisture))) and (sensor with optical)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/13 12:00
-	0	(optical adj fiber) with (sensor or detector) with housing with ((discharg\$3 or vent\$3 or remov\$3 or purg\$3) with (dew or condensation or moisture))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/13 12:01
-	68	(sensor or detector) with housing with ((discharg\$3 or vent\$3 or remov\$3 or purg\$3) with (dew or condensation or moisture))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/13 12:02
-	1	((sensor or detector) with housing with ((discharg\$3 or vent\$3 or remov\$3 or purg\$3) with (dew or condensation or moisture))) and (optical adj fiber)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/13 12:03
-	15	(purg\$3 with condensat\$3) and (optical adj fiber)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/13 12:05
-	0	(purg\$3 with condensat\$3) and (optical adj fiber adj sensor)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/13 12:05

-	3	(purg\$3 with (moisture or condensat\$3)) and (optical adj fiber adj sensor)	USPAT; US-PGPUB;	2004/05/13 12:08
			EPO; JPO; DERWENT;	
			IBM_TDB	
_	988	(purg\$3 with remov\$3 with (moisture or condensat\$3))	USPAT;	2004/05/13 12:08
			US-PGPUB;	
			EPO; JPO;	
			DERWENT; IBM_TDB	
_	0	((purg\$3 with remov\$3 with (moisture or condensat\$3))) and	USPAT:	2004/05/13 12:09
		(optical adj fiber adj sensor)	US-PGPUB;	200 1100/10 12:00
			EPO; JPO;	
			DERWENT;	
_	3147	optical adj fiber adj sensor	IBM_TDB USPAT;	2004/05/13 12:09
-	3147	optical adj liber adj serisor	US-PGPUB;	2004/05/13 12.09
			EPO; JPO;	
			DERWENT;	
		(and had a different by the company of the company	IBM_TDB	
_	4	(optical adj fiber adj sensor) with (purg\$3 or vent\$3)	USPAT;	2004/05/13 12:11
			US-PGPUB; EPO; JPO;	
			DERWENT;	
			IBM_TDB	
-	598	134/113.ccls.	USPAT;	2004/05/13 12:11
			US-PGPUB;	
			EPO; JPO; DERWENT;	
			IBM_TDB	
-	6	134/113.ccls. and ((purg\$3 or vent\$3 or discharg\$3) with	USPAT;	2004/05/13 15:39
		(moisture or condensat\$3))	US-PGPUB;	
			EPO; JPO;	
			DERWENT; IBM_TDB	
_	2	(optical adj sensor adj (unit or housing)) and ((purg\$3 or	USPAT;	2004/05/13 12:14
		vent\$3 or discharg\$3) with (moisture or condensat\$3))	US-PGPUB;	200 1700 12:11
			EPO; JPO;	
			DERWENT;	
_	1	(optical adj sensor adj (unit or housing)) and 134/\$.ccls.	IBM_TDB USPAT;	2004/05/13 12:15
		(option day conton day (write or floading)) and formations.	US-PGPUB;	2004/03/13 12.13
			EPO; JPO;	
			DERWENT;	
_	5	(optical adj fiber adj sensor) and 134/\$.ccls.	IBM_TDB USPAT;	2004/05/42 40:40
		(ορτίου αυ) πρετ αυ) σετίσοι / από 134/φ.ccis.	US-PGPUB;	2004/05/13 12:16
			EPO; JPO;	
			DERWENT;	
	20	(ontical adj fibor adj concer) with (-1-1	IBM_TDB	0004/05/15 15 15
-	20	(optical adj fiber adj sensor) with (station or bath)	USPAT; US-PGPUB;	2004/05/13 12:19
			EPO; JPO;	
			DERWENT;	
			IBM_TDB	
-	2	(optical adj fiber adj sensor) and (wet adj clean adj (station or	USPAT;	2004/05/13 13:00
		bath))	US-PGPUB; EPO; JPO;	
			DERWENT;	İ
			IBM_TDB	
-	2	(optical adj sensor) and (wet adj clean adj (station or bath))	USPAT;	2004/05/13 13:00
			US-PGPUB;	
			EPO; JPO; DERWENT;	
		<u> </u>	IBM_TDB	

US-PGPUB FPC, JPC DERWENT IBM TDB USFAT US-PGPUB EPC JPC					
- \$46 (optical adj sensor adj (unit or housing)) - 20 ((optical adj sensor adj (unit or housing))) and (moisture or condensat\$3 or dew) - 20 ((optical adj sensor adj (unit or housing))) and (moisture or condensat\$3 or dew) - 290 ((optical adj sensor adj (unit or housing))) and (moisture or condensat\$3 or dew) - 290 ((optical adj sensor adj (unit or housing))) and (moisture or condensat\$3 or dew) - 290 ((optical adj sensor adj (unit or housing))) and (moisture or condensat\$3 or dew) - 290 ((optical adj sensor adj (unit or housing))) and (moisture or condensat\$3)) - 290 ((optical adj sensor adj (unit or housing))) and (moisture or condensat\$3)) - 290 ((optical adj sensor adj (unit or housing))) and (part or condensat\$3)) - 290 ((optical adj sensor adj (unit or housing))) and (part or condensat\$3)) - 290 ((optical adj sensor adj (unit or housing))) and (part or condensat\$3)) - 290 ((optical adj sensor adj (unit or housing))) and (part or dew or condensat\$3)) - 290 ((optical adj sensor adj (unit or housing))) and (part or dew or condensat\$3)) - 304/104.1.ccls. and (purg\$3 with (moisture or dew or condensat\$3)) uspart (part of the condensat\$3)) - 290 (134/104.1.ccls. and ((purg\$3 or vent\$3) and (bath or station or vessel or tank) - 290 (134/104.1.ccls. and (sens\$3 or detect\$3) and (bath or station or vessel or tank) - 291 (134/104.1.ccls. and (sens\$3 or detect\$3) and (bath or station or vessel or tank) - 291 (134/104.1.ccls. and (sens\$3 or detect\$3) and (bath or station or vessel or tank) - 292 (134/104.1.ccls. and (sens\$3 or detect\$3) and (bath or station or vessel or tank) - 293 (134/104.1.ccls. and (sens\$3 or detect\$3) and (bath or station or vessel or tank) - 294 (134/104.1.ccls. and (sens\$3 or detect\$3) and (bath or station or vessel or tank) - 295 (134/104.1.ccls. and (sens\$3 or detect\$3) and (bath or station or vessel or tank) - 296 (134/104.1.ccls. and (sens\$3 or detect\$3) and (bath or station or vessel or tank) - 297 (134/104.1.ccls. and (sens\$3 or detect\$3) and (bath or station or ve	-	4	(optical adj2 sensor) and (wet adj clean adj (station or bath))		2004/05/13 13:01
S46 Coptical adj sensor adj (unit or housing)) SPAT; US-PGPUB; EPO, JPO; DERWENT; ISPAT; US-PGPUB; EPO, JPO; DERWENT; ISPAT; US-PGPUB; EPO, JPO; DERWENT; IBM, TDB; US-P					
Coptical adj sensor adj (unit or housing)					
- 20 ((optical adj sensor adj (unit or housing))) and (moisture or condensat\$3 or dew) - 290 ((optical adj sensor adj (unit or housing))) and (moisture or condensat\$3 or dew) - 290 134/104.1.ccls. 2004/05/13 13.36 USPAT; US-PGPUB; EPO, JPO, DERWENT; IBM TDB USPAT; US-PGPUB; EPO, JPO,	_	546	(optical adj sensor adj (unit or housing))		2004/05/13 13:28
DERWENT: IBM TDB USPAT: US-PGPUB: EPC; JPO: DERWENT: IBM TDB USPAT: US-PGPUB: EPC;			,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,	US-PGPUB;	
20					
20					
- 290 134/104.1.ccls. 2004/05/13 13:37 US-PGPUB. EPO, JPO, DERWENT, IBM TDB USPAT: US-PGPUB. EPO, JPO, DERWENT	_	20	((optical adi sensor adi (unit or housing))) and (moisture or	USPAT:	2004/05/13 13:36
- 290 134/104.1.ccls. 2 134/104.1.ccls. 2 134/104.1.ccls. 2 134/104.1.ccls. 2 134/104.1.ccls. 2 2 134/104.1.ccls. 2 2 134/104.1.ccls. 3 34/104.1.ccls.					
290 134/104.1.ccls. 134/104.1.ccls. 134/104.1.ccls. 204/05/13 13:37 US-PGPUB; EPC. J.PO. DERWENT; IBM. TDB USPAT; US-PGPUB; EPC. J.PO. DERWENT; IBM. TDB USPAT; US-PGPUB; EPC. J.PO. DERWENT; IBM. TDB USPAT; US-PGPUB; EPC. J.PO. DERWENT; IBM. TDB USPAT; US-PGPUB; EPO. J.PO. DERWENT; IBM.					
290 134/104.1.ccls. USPAT: US-PGPUB; EPO, JPO; DERWENT; IBM TDB USPAT; US-PGFUB; EPO; JPO; DERWENT; IBM TDB USPAT; US-PGFUB; EPO; JPO; DERWENT; IBM, T					
S-PGPUB; EPQ. JPO: DERWENT; IBM_TDB USPAT; US-PGPUB; EPQ. JPO: D	l _	290	134/104 1 ccls		2004/05/13 13:37
2		200	10-1/10-1.1.0010.		2004/03/13 10:5/
BM TDB USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB USPAT; US-P					
2 134/104.1.ccls. and (purg\$3 with (moisture or dew or condensat\$3)) USPAT; USPGPUB; EPC: JPO; DERWENT; IBM TDB USPAT; USPGPUB; EPO; JPO; DERWENT; I					
- 279		,	134/104 1 cds, and (purg\$3 with (moisture or dew or		2004/05/13 12:42
Septiment Sept					2004/03/13 13:42
134/104.1.ccls. and ((purg\$3 or vent\$3 or discharg\$3) with (moisture or dew or condensat\$3))				EPO; JPO;	
134/104.1.ccls. and ((purg\$3 or vent\$3) or discharg\$3) with (moisture or dew or condensat\$3))					
Company Comp		5	134/104 1 ccls, and (/nurg\$3 or yent\$3 or discharg\$3) with		2004/05/12 15:00
- 29 134/104.1.ccls. and ((moisture or dew or condensat\$3)) - 46 134/104.1.ccls. and (sens\$3 or detect\$3) and (bath or station or vessel or tank) - 21 (134/104.1.ccls. and (sens\$3 or detect\$3) and (bath or station or vessel or tank)) - 78446 422/\$.ccls 78446 422/\$.ccls 78 422/\$.ccls. and (optical adj2 sensor) and ((gas or nitrogen) with (flow\$3 or purg\$3 or discharg\$3 or vent\$3)) - 78 (422/\$.ccls. and (optical adj2 sensor) and ((gas or nitrogen) with (flow\$3 or purg\$3 or discharg\$3 or vent\$3))) and (moisture or condensat\$3 or dew) - 3655 (semiconductor or wafer or substrate) with (optical adj2 sensor) - 3655 (semiconductor or wafer or substrate) with (optical adj2 sensor) DERWENT; IBM_TDB USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB USPAT; US-PGPUB; EPO;	_				2004/05/15 15.09
- 29			(**************************************		
- 46 134/104.1.ccls. and ((moisture or dew or condensat\$3)) - 46 134/104.1.ccls. and (sens\$3 or detect\$3) and (bath or station or vessel or tank) - 21 (134/104.1.ccls. and (sens\$3 or detect\$3) and (bath or station or vessel or tank)) and (gas or nitrogen or N2) - 78446 422/\$.ccls 78446 422/\$.ccls 279 422/\$.ccls. and (optical adj2 sensor) and ((gas or nitrogen) with (flow\$3 or purg\$3 or discharg\$3 or vent\$3)) - 78 422/\$.ccls. and (optical adj2 sensor) and ((gas or nitrogen) with (flow\$3 or purg\$3 or discharg\$3 or vent\$3)) - 78 (422/\$.ccls. and (optical adj2 sensor) and ((gas or nitrogen) with (flow\$3 or purg\$3 or discharg\$3 or vent\$3)) and (moisture or condensat\$3 or dew) - 78 (semiconductor or wafer or substrate) with (optical adj2 sensor) EPO; JPO; DERWENT; IBM_TDB USPAT; US-PGPUB; EPO; JPO; DERW					
- 46 134/104.1.ccls. and (sens\$3 or detect\$3) and (bath or station or vessel or tank) - 21 (134/104.1.ccls. and (sens\$3 or detect\$3) and (bath or station or vessel or tank) - 21 (134/104.1.ccls. and (sens\$3 or detect\$3) and (bath or station or vessel or tank)) and (gas or nitrogen or N2) - 78446 422/\$.ccls. - 78446 422/\$.ccls. 279 422/\$.ccls. and (optical adj2 sensor) and ((gas or nitrogen) with (flow\$3 or purg\$3 or discharg\$3 or vent\$3)) - 78 (422/\$.ccls. and (optical adj2 sensor) and ((gas or nitrogen) with (flow\$3 or purg\$3 or discharg\$3 or vent\$3)) - 78 (422/\$.ccls. and (optical adj2 sensor) and ((gas or nitrogen) with (flow\$3 or purg\$3 or discharg\$3 or vent\$3)) - 8 (422/\$.ccls. and (optical adj2 sensor) and ((gas or nitrogen) with (flow\$3 or purg\$3 or discharg\$3 or vent\$3))) and (moisture or condensat\$3 or dew) - 8 (semiconductor or wafer or substrate) with (optical adj2 sensor) - 9 (semiconductor or wafer or substrate) with (optical adj2 sensor) - 10 (semiconductor or wafer or substrate) with (optical adj2 sensor) - 11 (semiconductor or wafer or substrate) with (optical adj2 sensor) - 12 (semiconductor or wafer or substrate) with (optical adj2 sensor) - 13 (semiconductor or wafer or substrate) with (optical adj2 sensor) - 14 (semiconductor or wafer or substrate) with (optical adj2 sensor) - 15 (semiconductor or wafer or substrate) with (optical adj2 sensor) - 15 (semiconductor or wafer or substrate) with (optical adj2 sensor)		20	134/104 1 cels, and (/moisture or dew or condensat\$3))		2004/05/12 14:10
- 46 134/104.1.ccls. and (sens\$3 or detect\$3) and (bath or station or vessel or tank) - 21 (134/104.1.ccls. and (sens\$3 or detect\$3) and (bath or station or vessel or tank) - 21 (134/104.1.ccls. and (sens\$3 or detect\$3) and (bath or station or vessel or tank)) and (gas or nitrogen or N2) - 78446 422/\$.ccls. - 78446 422/\$.ccls. - 279 422/\$.ccls. and (optical adj2 sensor) and ((gas or nitrogen) with (flow\$3 or purg\$3 or discharg\$3 or vent\$3)) - 78 (422/\$.ccls. and (optical adj2 sensor) and ((gas or nitrogen) with (flow\$3 or purg\$3 or discharg\$3 or vent\$3))) and (moisture or condensat\$3 or dew) - 3655 (semiconductor or wafer or substrate) with (optical adj2 sensor). - 3655 (semiconductor or wafer or substrate) with (optical adj2 sensor). - 3656 (semiconductor or wafer or substrate) with (optical adj2 sensor). - 3657 (semiconductor or wafer or substrate) with (optical adj2 sensor). - 3658 (semiconductor or wafer or substrate) with (optical adj2 sensor). - 3659 (semiconductor or wafer or substrate) with (optical adj2 sensor). - 3650 (semiconductor or wafer or substrate) with (optical adj2 sensor). - 3650 (semiconductor or wafer or substrate) with (optical adj2 sensor). - 3650 (semiconductor or wafer or substrate).		23	(moisture of dew of condensatios))		2004/03/13 14.10
- 46					
- 46 134/104.1.ccls. and (sens\$3 or detect\$3) and (bath or station or vessel or tank) - 21 (134/104.1.ccls. and (sens\$3 or detect\$3) and (bath or station or vessel or tank)) and (gas or nitrogen or N2) - 78446 422/\$.ccls. - 78446 422/\$.ccls. and (optical adj2 sensor) and ((gas or nitrogen) with (flow\$3 or purg\$3 or discharg\$3 or vent\$3)) - 78 (422/\$.ccls. and (optical adj2 sensor) and ((gas or nitrogen) with (flow\$3 or purg\$3 or discharg\$3 or vent\$3)) and (moisture or condensat\$3 or dew) - 3655 (semiconductor or wafer or substrate) with (optical adj2 sensor) - 3655 (semiconductor or wafer or substrate) with (optical adj2 sensor). - 27 (semiconductor or wafer or substrate) with (optical adj2 sensor). - 365 (semiconductor or wafer or substrate) with (optical adj2 sensor). - 365 (semiconductor or wafer or substrate) with (optical adj2 sensor). - 365 (semiconductor or wafer or substrate) with (optical adj2 sensor). - 365 (semiconductor or wafer or substrate).				1	
or vessel or tank) - 21 (134/104.1.ccls. and (sens\$3 or detect\$3) and (bath or station or vessel or tank)) and (gas or nitrogen or N2) - 78446 422/\$.ccls. - 78446 422/\$.ccls. - 279 422/\$ ccls. and (optical adj2 sensor) and ((gas or nitrogen) with (flow\$3 or purg\$3 or discharg\$3 or vent\$3)) - 78 (422/\$.ccls. and (optical adj2 sensor) and ((gas or nitrogen) with (flow\$3 or purg\$3 or discharg\$3 or vent\$3)) - 3655 (semiconductor or wafer or substrate) with (optical adj2 sensor) - 3655 (semiconductor or wafer or substrate) with (optical adj2 sensor) - 3656 (semiconductor or wafer or substrate) with (optical adj2 sensor) operwent; EPO; JPO; DERWENT; IBM_TDB USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB USPAT; US-PGPU	_	46	134/104 1 ccls, and (sens\$3 or detect\$3) and (bath or station		2004/05/13 14:14
- 21 (134/104.1.ccls. and (sens\$3 or detect\$3) and (bath or station or vessel or tank)) and (gas or nitrogen or N2) - 78446 422/\$.ccls. 279 422/\$.ccls. and (optical adj2 sensor) and ((gas or nitrogen) with (flow\$3 or purg\$3 or discharg\$3 or vent\$3)) - 78 (422/\$.ccls. and (optical adj2 sensor) and ((gas or nitrogen) with (flow\$3 or purg\$3 or discharg\$3 or vent\$3))) and (moisture or condensat\$3 or dew) - 3655 (semiconductor or wafer or substrate) with (optical adj2 sensor) PPO; JPO; DERWENT; IBM_TDB USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB US-PAT; US-P					2004/05/15 14:14
- 21 (134/104.1.ccls. and (sens\$3 or detect\$3) and (bath or station or vessel or tank)) and (gas or nitrogen or N2) - 78446 422/\$.ccls. - 279 422/\$.ccls. and (optical adj2 sensor) and ((gas or nitrogen) with (flow\$3 or purg\$3 or discharg\$3 or vent\$3)) - 78 (422/\$.ccls. and (optical adj2 sensor) and ((gas or nitrogen) with (flow\$3 or purg\$3 or discharg\$3 or vent\$3))) and ((moisture or condensat\$3 or dew) - 3655 (semiconductor or wafer or substrate) with (optical adj2 sensor); lbm_TDB USPAT; US-PGPUB; EPO; JPO; DERWENT; lbm_TDB USPAT;					
- 21 (134/104.1.ccls. and (sens\$3 or detect\$3) and (bath or station or vessel or tank)) and (gas or nitrogen or N2) - 78446 422/\$.ccls. - 279 422/\$.ccls. and (optical adj2 sensor) and ((gas or nitrogen) with (flow\$3 or purg\$3 or discharg\$3 or vent\$3)) - 78 (422/\$.ccls. and (optical adj2 sensor) and ((gas or nitrogen) with (flow\$3 or purg\$3 or discharg\$3 or vent\$3)) - 3655 (semiconductor or wafer or substrate) with (optical adj2 sensor) - 3655 (semiconductor or wafer or substrate) with (optical adj2 sensor) - 3655 (semiconductor or wafer or substrate) with (optical adj2 sensor) - 3655 (semiconductor or wafer or substrate) with (optical adj2 sensor) - 3655 (semiconductor or wafer or substrate) with (optical adj2 sensor) - 3655 (semiconductor or wafer or substrate) with (optical adj2 sensor) - 3656 (semiconductor or wafer or substrate) with (optical adj2 sensor) - 3657 (semiconductor or wafer or substrate) with (optical adj2 sensor) - 3657 (semiconductor or wafer or substrate) with (optical adj2 sensor) - 3658 (semiconductor or wafer or substrate) with (optical adj2 sensor) - 3659 (semiconductor or wafer or substrate) with (optical adj2 sensor) - 3650 (semiconductor or wafer or substrate) with (optical adj2 sensor) - 3650 (semiconductor or wafer or substrate) with (optical adj2 sensor) - 3650 (semiconductor or wafer or substrate) with (optical adj2 sensor) - 3650 (semiconductor or wafer or substrate) with (optical adj2 sensor) - 3650 (semiconductor or wafer or substrate) with (optical adj2 sensor)					
or vessel or tank)) and (gas or nitrogen or N2) - 78446 422/\$.ccls. 279 422/\$.ccls. and (optical adj2 sensor) and ((gas or nitrogen) with (flow\$3 or purg\$3 or discharg\$3 or vent\$3)) - 78 (422/\$.ccls. and (optical adj2 sensor) and ((gas or nitrogen) with (flow\$3 or purg\$3 or discharg\$3 or vent\$3)) - 78 (422/\$.ccls. and (optical adj2 sensor) and ((gas or nitrogen) with (flow\$3 or purg\$3 or discharg\$3 or vent\$3))) and (moisture or condensat\$3 or dew) - 3655 (semiconductor or wafer or substrate) with (optical adj2 sensor) Semsor) US-PGPUB; EPO; JPO; DERWENT; IBM_TDB USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB USPAT; US-PGPUB; EPO; JPO; DERWENT;	_	21	(134/104.1.ccls, and (sens\$3 or detect\$3) and (bath or station		2004/05/13 13:48
- 78446 422/\$.ccls.					200 1/00/10 10:10
- 78446 422/\$.ccls. IBM_TDB USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB USPAT; US-PGPUB; EPO; JPO; DERWENT; ISPAT; US-PGPUB; ISPAT; US-PGPUB; ISPAT; US-PGPUB; ISPAT; US-PGPUB; ISPAT; US-PGPUB; ISPAT; US-PGPUB; ISPAT;					
- 78446 422/\$.ccls.					
- 279 422/\$.ccls. and (optical adj2 sensor) and ((gas or nitrogen) with (flow\$3 or purg\$3 or discharg\$3 or vent\$3)) - 78 (422/\$.ccls. and (optical adj2 sensor) and ((gas or nitrogen) with (flow\$3 or purg\$3 or discharg\$3 or vent\$3)) - 3655 (semiconductor or wafer or substrate) with (optical adj2 sensor) - 3655 (semiconductor or wafer or substrate) with (optical adj2 sensor) - 3655 (semiconductor or wafer or substrate) with (optical adj2 sensor) - 3656 (semiconductor or wafer or substrate) with (optical adj2 sensor) - 3657 (semiconductor or wafer or substrate) with (optical adj2 sensor) - 3658 (semiconductor or wafer or substrate) with (optical adj2 sensor) - 3659 (semiconductor or wafer or substrate) with (optical adj2 sensor) - 3659 (semiconductor or wafer or substrate) with (optical adj2 sensor) - 3650 (semiconductor or wafer or substrate) with (optical adj2 sensor) - 3650 (semiconductor or wafer or substrate) with (optical adj2 sensor)	_	78446	422/\$.ccls.		2004/05/13 13:52
- 279 422/\$.ccls. and (optical adj2 sensor) and ((gas or nitrogen) with (flow\$3 or purg\$3 or discharg\$3 or vent\$3)) - 78 (422/\$.ccls. and (optical adj2 sensor) and ((gas or nitrogen) with (flow\$3 or purg\$3 or discharg\$3 or vent\$3))) and (moisture or condensat\$3 or dew) - 3655 (semiconductor or wafer or substrate) with (optical adj2 sensor) - 3655 (semiconductor or wafer or substrate) with (optical adj2 sensor) - 3656 (semiconductor or wafer or substrate) with (optical adj2 sensor) - 3657 (semiconductor or wafer or substrate) with (optical adj2 sensor) - 3658 (semiconductor or wafer or substrate) with (optical adj2 sensor) - 3659 (semiconductor or wafer or substrate) with (optical adj2 sensor) - 3659 (semiconductor or wafer or substrate) with (optical adj2 sensor) - 3650 (semiconductor or wafer or substrate) with (optical adj2 sensor) - 3650 (semiconductor or wafer or substrate) with (optical adj2 sensor) - 3650 (semiconductor or wafer or substrate) with (optical adj2 sensor) - 3650 (semiconductor or wafer or substrate) with (optical adj2 sensor) - 3650 (semiconductor or wafer or substrate) with (optical adj2 sensor) - 3650 (semiconductor or wafer or substrate) with (optical adj2 sensor)			'		200 1.00.10 10.02
- 279 422/\$.ccls. and (optical adj2 sensor) and ((gas or nitrogen) with (flow\$3 or purg\$3 or discharg\$3 or vent\$3)) - 78 (422/\$.ccls. and (optical adj2 sensor) and ((gas or nitrogen) with (flow\$3 or purg\$3 or discharg\$3 or vent\$3))) and ((gas or nitrogen) with (flow\$3 or purg\$3 or discharg\$3 or vent\$3))) and ((gas or nitrogen) with (flow\$3 or purg\$3 or discharg\$3 or vent\$3))) and ((gas or nitrogen) USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB USPAT; US-PGPUB; EPO; JPO; DERWENT; US-PGPUB; EPO; JPO; DERWENT; US-PGPUB; EPO; JPO; DERWENT;					
- 279 422/\$.ccls. and (optical adj2 sensor) and ((gas or nitrogen) with (flow\$3 or purg\$3 or discharg\$3 or vent\$3)) 78 (422/\$.ccls. and (optical adj2 sensor) and ((gas or nitrogen) DERWENT; IBM_TDB USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB USPAT; US-PGPUB; EPO; JPO; DERWENT; US-PGPUB; E					
with (flow\$3 or purg\$3 or discharg\$3 or vent\$3)) 78 (422/\$.ccls. and (optical adj2 sensor) and ((gas or nitrogen) with (flow\$3 or purg\$3 or discharg\$3 or vent\$3))) and (moisture or condensat\$3 or dew) 9 (semiconductor or wafer or substrate) with (optical adj2 sensor) 10 (Gas or nitrogen) USPAT; USPAT; USPGPUB; EPO; JPO; DERWENT; IBM_TDB USPAT; USPAT; USPAT; USPGPUB; EPO; JPO; DERWENT; USPGPUB; EPO; JPO; DERWENT; USPGPUB; EPO; JPO; DERWENT;	_	279	422/\$.ccls. and (optical adj2 sensor) and ((gas or nitrogen)		2004/05/13 14:04
The sensor of th			with (flow\$3 or purg\$3 or discharg\$3 or vent\$3))	US-PGPUB;	
- 3655 (422/\$.ccls. and (optical adj2 sensor) and ((gas or nitrogen) with (flow\$3 or purg\$3 or discharg\$3 or vent\$3))) and (moisture or condensat\$3 or dew) Semiconductor or wafer or substrate) with (optical adj2 sensor) IBM_TDB USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB USPAT; US-PGPUB; EPO; JPO; DERWENT; US-PGPUB; EPO; JPO; DERWENT;				1 '	
78 (422/\$.ccls. and (optical adj2 sensor) and ((gas or nitrogen) with (flow\$3 or purg\$3 or discharg\$3 or vent\$3))) and (moisture or condensat\$3 or dew) 3655 (semiconductor or wafer or substrate) with (optical adj2 sensor) USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB USPAT; US-PGPUB; EPO; JPO; DERWENT; US-PGPUB; EPO; JPO; DERWENT;				1	
with (flow\$3 or purg\$3 or discharg\$3 or vent\$3))) and (moisture or condensat\$3 or dew) - 3655 (semiconductor or wafer or substrate) with (optical adj2 sensor) US-PGPUB; EPO; JPO; DERWENT; IBM_TDB USPAT; US-PGPUB; EPO; JPO; DERWENT;	_	78	(422/\$.ccls. and (optical adj2 sensor) and ((gas or nitrogen)	USPAT:	2004/05/13 14:03
DERWENT; IBM_TDB USPAT; US-PGPUB; EPO; JPO; DERWENT;			with (flow\$3 or purg\$3 or discharg\$3 or vent\$3))) and	US-PGPUB;	
- 3655 (semiconductor or wafer or substrate) with (optical adj2 USPAT; US-PGPUB; EPO; JPO; DERWENT;			(moisture or condensat\$3 or dew)		
- 3655 (semiconductor or wafer or substrate) with (optical adj2 USPAT; US-PGPUB; EPO; JPO; DERWENT;					
sensor) US-PGPUB; EPO; JPO; DERWENT;	-	3655	(semiconductor or wafer or substrate) with (optical adj2		2004/05/13 14:05
DERWENT;				US-PGPUB;	
				IBM_TDB	

_	398	((semiconductor or wafer or substrate) with (optical adj2 sensor)) and ((gas or nitrogen) with (flow\$3 or purg\$3 or discharg\$3 or vent\$3))	USPAT; US-PGPUB; EPO; JPO;	2004/05/13 14:06
			DERWENT;	
	59	(comicondustor or wafer or substrate) with (tank or vessel or	IBM_TDB	2004/05/40 44 05
-	39	(semiconductor or wafer or substrate) with (tank or vessel or bath or station) with (optical adj2 sensor)	USPAT; US-PGPUB;	2004/05/13 14:05
		batti of station, with (optical adjz sensor)	EPO; JPO;	
			DERWENT;	
			IBM TDB	
-	11	((semiconductor or wafer or substrate) with (tank or vessel or	USPAT;	2004/05/13 14:06
		bath or station) with (optical adj2 sensor)) and ((gas or	US-PGPUB;	
		nitrogen) with (flow\$3 or purg\$3 or discharg\$3 or vent\$3))	EPO; JPO;	
			DERWENT;	lli
		40.4440 1 1.44 40 10 10 10 10 10 10	IBM_TDB	
-	6	134/113.ccls. and ((purg\$3 or vent\$3 or discharg\$3) with	USPAT;	2004/05/13 14:10
		(moisture or dew or condensat\$3))	US-PGPUB;	
			EPO; JPO; DERWENT;	
			IBM_TDB	
-	40	134/113.ccls. and ((moisture or dew or condensat\$3))	USPAT;	2004/05/13 14:10
		(())))))))))))))))))	US-PGPUB;	20000, 10 14.10
			EPO; JPO;	
			DERWENT;	
			IBM_TDB	
-	212	134/113.ccls. and (sens\$3 or detect\$3) and (bath or station or	USPAT;	2004/05/13 14:14
		vessel or tank)	US-PGPUB;	
			EPO; JPO; DERWENT;	
	İ		IBM_TDB	
_	109	134/113.ccls. and (sens\$3 or detect\$3) with (bath or station or	USPAT:	2004/05/13 14:15
		vessel or tank)	US-PGPUB;	200 1700710 11:10
			EPO; JPO;	
	i		DERWENT;	
	_	404/440 and a result (/author)	IBM_TDB	
-	5	134/113.ccls. and ((optical near2 (sens\$3 or detect\$3)) with	USPAT;	2004/05/13 14:16
		(bath or station or vessel or tank))	US-PGPUB; EPO; JPO;	
			DERWENT;	
		,	IBM_TDB	
=	33	(fixing adj guide) with (bath or tank or vessel or station)	USPAT;	2004/05/13 14:19
			US-PGPUB;	
			EPO; JPO;	
			DERWENT;	
_	29	((semiconductor or wafer or substrate) with (bath or tank or	IBM_TDB USPAT;	2004/05/13 14:20
	25	vessel or station) with (optical near2 (sens\$3 or detect\$3)))	US-PGPUB;	2004/03/13 14.20
		and (gas or nitrogen or N2)	EPO; JPO;	
		·	DERWENT;	
			IBM_TDB	
-	107	(semiconductor or wafer or substrate) with (bath or tank or	USPAT;	2004/05/13 15:06
		vessel or station) with (optical near2 (sens\$3 or detect\$3))	US-PGPUB;	
			EPO; JPO;	
			DERWENT; IBM_TDB	
-	5	((semiconductor or wafer or substrate) with (bath or tank or	USPAT;	2004/05/13 14:57
		vessel or station) with (optical near2 (sens\$3 or detect\$3)))	US-PGPUB;	
		and 134/\$.ccls.	EPO; JPO;	
			DERWENT;	
		Magnison division an uniform an auto-to-to-) (M. A. M. M. M. M. M. M. M. M. M. M. M. M. M.	IBM_TDB	0004105415
-	3	((semiconductor or wafer or substrate) with (bath or tank or vessel or station) with (optical near2 (sens\$3 or detect\$3)))	USPAT;	2004/05/13 15:13
		and 451/\$.ccls.	US-PGPUB; EPO; JPO;	
			DERWENT;	
			IBM_TDB	

· · · ·				
-	65	134/104.1.ccls. and (purg\$3 or vent\$3 or discharg\$3) and (sens\$3 or detect\$3)	USPAT; US-PGPUB;	2004/05/13 15:10
			EPO; JPO; DERWENT;	
_	4	(wet adj clean adj (station or tank or vessel)) and (optical adj2	IBM_TDB USPAT;	2004/05/13 15:12
		(sens\$3 or detect\$3))	US-PGPUB;	255 1100, 10 10, 12
			EPO; JPO; DERWENT;	
			IBM_TDB	
-	8	(wet adj clean adj (station or tank or vessel)) and ((sens\$3 or detect\$3))	USPAT; US-PGPUB:	2004/05/13 15:16
			EPO; JPO;	
!			DERWENT; IBM_TDB	
-	2	((semiconductor or wafer or substrate) with (bath or tank or vessel or station) with (optical near2 (sens\$3 or detect\$3)))	USPAT; US-PGPUB;	2004/05/13 15:13
		and 438/\$.ccls.	EPO; JPO;	
			DERWENT; IBM_TDB	
- !	12	wet adj clean adj station	USPAT;	2004/05/13 15:16
			US-PGPUB; EPO; JPO;	
			DERWENT;	
_	8	(wet adj clean adj station) and (sens\$3 or detect\$3)	IBM_TDB USPAT;	2004/05/13 15:24
			US-PGPUB;	
			EPO; JPO; DERWENT;	
_	82	68/\$.ccls. and (turbid\$3 near2 (sens\$3 or detect\$3))	IBM_TDB USPAT;	2004/05/13 15:39
		solvisors and (tarefage floar)	US-PGPUB;	2004/03/13 13:39
			EPO; JPO; DERWENT;	
	229	69/42 03 colo	IBM_TDB	0004/05/40 45 00
-	229	68/12.02.ccls.	USPAT; US-PGPUB;	2004/05/13 15:26
			EPO; JPO;	
			DERWENT; IBM_TDB	
-	60	68/12.02.ccls. and ((turbid\$3 or optical) with (detect\$3 or sens\$3))	USPAT; US-PGPUB;	2004/05/13 15:26
			EPO; JPO;	
			DERWENT; IBM TDB	
-	22	(68/\$.ccls. and (turbid\$3 near2 (sens\$3 or detect\$3))) and ((purg\$3 or vent\$3 or discharg\$3))	USPAT; US-PGPUB;	2004/05/13 15:41
		((pa. 945 3) Voltage of alcohologyo))	EPO; JPO;	
			DERWENT; IBM_TDB	
-	265	(optical near2 (sens\$3 or detect\$3) and ((purg\$3 or vent\$3 or	USPAT;	2004/05/13 15:43
		discharg\$3 or remov\$3) with (condensat\$3)))	US-PGPUB; EPO; JPO;	
			DERWENT; IBM_TDB	
-	265	((optical near2 (sens\$3 or detect\$3)) and ((purg\$3 or vent\$3 or	USPAT;	2004/05/13 15:43
		discharg\$3 or remov\$3) with (condensat\$3)))	US-PGPUB; EPO; JPO;	
			DERWENT;	
-	47	((optical near2 (sens\$3 or detect\$3)) same ((purg\$3 or vent\$3	IBM_TDB USPAT;	2004/05/13 15:43
		or discharg\$3 or remov\$3) with (condensat\$3)))	US-PGPUB;	
			EPO; JPO; DERWENT;	
<u> </u>			IBM_TDB	